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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/813,687	03/31/2004	Patricius Aloysius Jacobus Tinnemans	081468-0308853	4349
909	7590	11/29/2005	EXAMINER	
PILLSBURY WINTHROP SHAW PITTMAN, LLP			NGUYEN, HUNG	
P.O. BOX 10500			ART UNIT	
MCLEAN, VA 22102			PAPER NUMBER	
			2851	

DATE MAILED: 11/29/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

DETAILED ACTION

Election/Restrictions

1. Restriction to one of the following inventions is required under 35 U.S.C. 121:
 - I. Claims 1-10, 15-18 and 21, drawn to a lithographic support system having a robot arm comprising a clamp and a compliant structure to compensate a tilt and displacement between object and the clamp, classified in class 355, subclass 72.
 - II. Claims 11-12, 19, 22 drawn to a electrostatic clamping structure for use in a lithography apparatus comprising a Johnson-Raybeck effect type clamp provided with an oxidize layer, classified in class 361, subclass 234.
 - III. Claims 13, and 20 drawn to a lithographic support structure for holding and moving an object comprising a Johnson-Raybeck effect type clamp configured with a DC and AC power supply controllers to effect respective clamping and de-clamping of an object, classified in class 361, subclass 235.
 - IV. Claim 14, drawn to a method of cleaning a substrate holder, classified in class 355, subclass 77.

The inventions are distinct, each from the other because of the following reasons:

2. Inventions I-IV are related as subcombinations disclosed as usable together in a single combination. The subcombinations are distinct from each other if they are shown to be separately usable. In the instant case, inventions I-IV have separate utilities such as utilizing a rotatable robot arm for accurately transporting and aligning the substrate in a photosensitive substrate processing system; holding an object in a laser machining apparatus using a Johnson-

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Raybeck type clamp with an oxidized layer for reducing the thermal expansion of the object, generating clamping voltage and declamping voltage for holding a substrate to an electrostatic chuck for minimizing the time of de-clamping, a method for cleaning a substrate by repeatedly clamping and declamping the substrate at more than one location of a positioning apparatus .

See MPEP § 806.05(d).

3. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art as shown by their different classification, restriction for examination purposes as indicated is proper.

4. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art because of their recognized divergent subject matter, restriction for examination purposes as indicated is proper.

5. Applicant is advised that the reply to this requirement to be complete must include an election of the invention to be examined even though the requirement be traversed (37 CFR 1.143).

6. Applicant is reminded that upon the cancellation of claims to a non-elected invention, the inventorship must be amended in compliance with 37 CFR 1.48(b) if one or more of the currently named inventors is no longer an inventor of at least one claim remaining in the application. Any amendment of inventorship must be accompanied by a request under 37 CFR 1.48(b) and by the fee required under 37 CFR 1.17(i).

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7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Hung Henry V. Nguyen whose telephone number is 571-272-2124. The examiner can normally be reached on Monday-Friday (First Friday off).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Judy Nguyen can be reached on 571-272-2258. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).



Hung Henry V Nguyen
Primary Examiner
Art Unit 2851

hvn
11/24/05